

FORM PTO-1449 (modified)
To: U.S. Department of Commerce
(PW FORM PAT-1449)
Patent and Trademark Office

Atty.
Dkt. No.

M#

308709

P-0224.011.US

**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

Applicant: GUI et al.

Appln. No.: NOT ASSIGNED

Filing Date: March 18, 2004

Date: March 18, 2004

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of

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Examiner: NOT
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Group Art Unit: NOT
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U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
P/L	AR 3,752,589 ✓	08/1973	Kobayashi			
	BR 4,046,985 ✓	09/1977	Gates			
	CR 4,408,875 ✓	10/1983	Majima			
	DR 4,798,470 ✓	01/1989	Moriyama et al.			
	ER 4,897,553 ✓	01/1990	Nishi			
	FR 4,952,060 ✓	08/1990	Ina et al.			
	GR 5,241,188	08/1993	Mizutani			
	HR 5,298,988 ✓	03/1994	Everett et al.			
	IR 5,361,132 ✓	11/1994	Farn			
	JR 5,530,552 ✓	06/1996	Mermagen et al.			
	KR 5,552,892	09/1996	Nagayama			
	LR 5,621,813	04/1997	Brown et al.			
	MR 5,821,549	10/1998	Talbot et al.			
	NR 5,843,831 ✓	12/1998	Chung et al.			
	OR 5,874,190 ✓	02/1999	Tanaka			
	PR 5,894,530 ✓	04/1999	Wilt			
	QR 5,929,997 ✓	07/1999	Lin			
	RR 5,936,711	08/1999	Miyai et al.			
	SR 5,978,069	11/1999	Kato			
P/L	TR 5,985,764 ✓	11/1999	Lin et al.			

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Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract	Translation Readily Available
				Enclosed	No
P/L	UR 0 756 207 A3	01/1997	Europe		
	VR 1-164032	06/1989	Japan		
	WR 3-246923	11/1991	Japan		
	XR 10-187937	07/1998	Japan		
	YR 10-209030	08/1998	Japan		
P/L	ZR 11-340120	12/1999	Japan		

OTHER: (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

P/L AAR Everett et al., "Aligning lithography on opposite surfaces of a substrate," *Applied Optics*, Vol. 31, No. 34, pp. 7292-7294, 1992.

BBR

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*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
ML	CCR 6,141,108	10/2000	Kida et al.			
	DDR 6,262,793	07/2001	Sasaya et al.			
	EER 6,376,329	04/2002	Sogard et al.			
ML	FFR 6,525,805	02/2003	Heinle			
	GGR					
	HHR					
	IIR					
	JJR					
	KKR					
	LLR					
	MMF					
	NNR					
	OOR					

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		Abstract		Readily Available	
							Enclosed	No	Enclose	No
	PPR									
	QQR									
	RRR									
	SSR									
	TTR									
	UUR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

2/L	VVR	Katagiri et al., "Novel Alignment Technique for 0.1- μ m Lithography Using the Wafer Rear Surface and Canceling Tilt Effect," <i>Optical Engineering</i> , Vol. 32, No. 10, pp. 2344-2349, 1993.			
	WW	Patent Abstracts of Japan, JP11340120, published December 1999.			
	XXR	Patent Abstracts of Japan, JP05144702, published June 1993.			
	YYR	Patent Abstracts of Japan, JP3246923, published November 1991.			
2/L	ZZR	Patent Abstracts of Japan, JP1164032, published June 1989.			
	AAA				
	BBB				

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